

Demis D John

List of Publications by Year in descending order

Source: <https://exaly.com/author-pdf/2197293/publications.pdf>

Version: 2024-02-01

13
papers

988
citations

1478505

6
h-index

1720034

7
g-index

13
all docs

13
docs citations

13
times ranked

1102
citing authors

| # | ARTICLE | IF | CITATIONS |
|----|--|-----|-----------|
| 1 | Ultra-low-loss high-aspect-ratio Si ₃ N ₄ waveguides. Optics Express, 2011, 19, 3163. | 3.4 | 414 |
| 2 | Planar waveguides with less than 01 dB/m propagation loss fabricated with wafer bonding. Optics Express, 2011, 19, 24090. | 3.4 | 367 |
| 3 | Wideband Electrically Pumped 1050-nm MEMS-Tunable VCSEL for Ophthalmic Imaging. Journal of Lightwave Technology, 2015, 33, 3461-3468. | 4.6 | 73 |
| 4 | Rapidly swept, ultra-widely-tunable 1060-1080 nm MEMS-VCSELs. Electronics Letters, 2012, 48, 1331. | 1.0 | 47 |
| 5 | Multilayer Platform for Ultra-Low-Loss Waveguide Applications. IEEE Photonics Technology Letters, 2012, 24, 876-878. | 2.5 | 37 |
| 6 | Deuterated silicon dioxide for heterogeneous integration of ultra-low-loss waveguides. Optics Letters, 2020, 45, 3340. | 3.3 | 21 |
| 7 | Ultra-low-loss Single-mode Si ₃ N ₄ Waveguides with 0.7 dB/m Propagation Loss. , 2011, , . | | 11 |
| 8 | Ultra-low loss silica-based waveguides with millimeter bend radius. , 2010, , . | | 9 |
| 9 | Highly selective and vertical etch of silicon dioxide using ruthenium films as an etch mask. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2021, 39, . | 2.1 | 7 |
| 10 | Ultra-low-loss (≤ 0.1 dB/m) Planar Silica Waveguide Technology. , 2011, , . | | 1 |
| 11 | Single-Mode and High-Speed 850nm MEMS-VCSEL. , 2016, , . | | 1 |
| 12 | Fabrication and Demonstration of a Pure Silica-Core Waveguide Utilizing a Density-Based Index Contrast. , 2011, , . | | 0 |
| 13 | High Extinction, Broadband, and Low Loss Planar Waveguide Polarizers. , 2012, , . | | 0 |